

(REVISED COURSE)

(3 Hours)

[Total Marks : 100

N.B. : (1) Question No. 1 is **compulsory**.(2) Attempt any **four** of the remaining **six** questions.(3) Assume **suitable data** wherever **necessary**.

1. (a) With the help of a neat diagram explain the important features of butting and buried contacts. 5
 (b) Explain IC crossovers. 5
 (c) List double metal MOS process rules. 5
 (d) How does a "dummy collector" prevent Latching? 5
2. (a) Discuss scaling factors for device parameters. 10
 (b) Describe the formation of resistors in integrated circuit. How will you optimize the design? 10
3. (a) Discuss the parasitic effects in BJTS. 10
 (b) Draw the stick diagram and a mask layout for an 8:1 nMOS inverter circuit both the input and output points should be on the polysilicon layer. 10
4. (a) With neat diagrams explain the fabrication sequence of CMOS inverter using the p-well process. 10
 (b) Calculate the native threshold voltage for an n-transistor at 300°K for a process with a Si-substrate with $N_A = 1.80 \times 10^{16}$, a SiO₂ gate oxide with thickness 200 Å.
 (Assume $\phi_{ms} = -0.9$ V, $Q_{fc} = 0$) 10
5. (a) What is photolithography? What are the different techniques involved in it? Explain one of them in detail. 10
 (b) Draw stick diagram and layout for nMOS shift register cell. 10
6. (a) In the inverter circuit, what is meant by $Z_{p,u}$ and $Z_{p,d}$? Derive the required ratio between $Z_{p,u}$ and $Z_{p,d}$ if an nMOS inverter is to be driven from another nMOS inverter. 10
 (b) What is epitaxy? What are the different epitaxial processes? Explain one of them in detail. 10
7. (a) What are the advantages of twin-tub process over n-well process? 5
 (b) Explain limitations of scaling. 5
 (c) Explain ion-implantation technique. 5
 (d) Explain significance of lambda-based design rules for MOS-IC. 5